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Fax Cover Sheet

DATÉ:

FROM:

November 16, 2002

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TO:

Examiner Tan N. Tran

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GAU 2826

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Message

DOCKET GS150

Please see attached:

Response to Restriction Requirement

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CONFIDENTIALITY NOTICE

II 7 Elective 11/19/or

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

luan Hshich et al.

Serial No.:

10/010,484

Filed:

November 20, 2001

Title:

Trench MOSFET Device with Polycrystalline Silicon Source Contact STructure

Art Unit:

2826

Examiner:

Tan N. Tran

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Docket No.:

GS 150

NOV 1 6 2002

Assistant Commissioner for Patents Washington, D.C. 20231

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RESPONSE TO RESTRICTION REQUIREMENT

Sir:

In response to the Office Action dated October 18, 2002, kindly consider the following response to the outstanding restriction requirement.

REMARKS

Claims 1-21 are pending in the application. Restriction was required to the following allegedly distinct inventions:

- I. Claims 1-16, drawn to a semiconductor device, classified in class 257, subclass 330.
- II. Claims 17-21, drawn to a method of manufacturing a semiconductor device, classified in class 438, subclass 259.

The Office Action indicates that the inventions are distinct because "the device of the group I invention could be make by a process materially different than that of the group II invention".